## ABSTRACT

- 1 A method for positioning substrates in a substrate
- 2 processing apparatus having a substrate alignment device,
- 3 a first substrate transport apparatus and a second
- 4 substrate transport apparatus, includes calibrating the
- 5 substrate alignment device with a motion of the first
- 6 substrate transport apparatus, and calibrating a
- 7 coordinate system of the second substrate transport
- 8 apparatus with the substrate alignment device.